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CHEMICAL MECHANICAL POLISHING PROCESS

Appl. No. : 10/711,392 Confirmation No. 5391
Applicant : Chia-Lin Hsu,
Teng-Chun Tsai
Filed : September 16, 2004
TC/A.U. : 3723
Examiner : Jacob K. Ackun Jr.
Docket No. : NAUP0633USA0
Customer No. : 27765

Commissioner for Patents
P.O. Box 1450
Alexandria VA 22313-1450

AMENDMENT

Sir:

In response to the Office action of July 5, 2005, please amend the above-identified
5 application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of
this paper.

Remarks/Arguments begin on page 4 of this paper.